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16 Rec'd PCT/PTO SEP 28 2001

L. Nelson  
#3/Pre Amdt A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE 11-30-01

In re application of:

KIUCHI et al.

Group Art Unit:

Serial No.: New Application

Examiner:

Filed: September 28, 2001

Docket No. P107242-00023

For: POLISHING APPARATUS AND METHOD

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
Washington, D.C. 20231

September 28, 2001

Sir:

Prior to calculation of the filing fee and prior to the examination of this application, please amend the above-identified application as follows:

**IN THE CLAIMS:**

Please cancel original claims 1-31 and add the following claims.

A1  
Sub B1  
✓

-- 32. (Added) A polishing apparatus comprising:  
a polishing table; and  
a work holding plate,  
wherein a work held on the work holding plate is polished supplying a  
polishing agent solution, and in polishing action, an amount of deformation of the polishing  
table in a direction normal to an upper surface thereof and/or an amount of deformation of  
the work holding plate in a direction normal to a work holding surface thereof is restricted to  
100  $\mu$ m or less.